

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Richard Schiek
Title: SYSTEM FOR GENERATING TWO-DIMENSIONAL MASKS
FROM A THREE-DIMENSIONAL MODEL USING
TOPOLOGICAL ANALYSIS
Serial No.: To Be Assigned Filing Date:
Examiner: To Be Assigned Group Art Unit: To Be Assigned
Docket No.: SD-7173

Albuquerque, New Mexico
September 11, 2003

Mail Stop Patent Application
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UNDER 37 CFR § 1.97(b)**

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3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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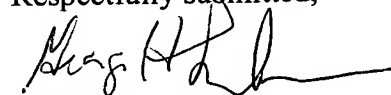
Viola Campos
(Signature)

VIOLA CAMPOS
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9/24/03
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Respectfully submitted,



George H. Libman
Attorney for Applicant(s)
Reg. No. 27,984

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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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Application Number	
Filing Date	9/24/03
First Named Inventor	Schiek, Richard
Art Unit	
Examiner Name	
Attorney Docket Number	SD-7173

Sheet 1 of 2

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
		US- 5,903,099	05-11-1999	Johnson et al.	
		US- 6,074,890	06-13-2000	Yao et al.	
		US- 6,082,208	07-04-2000	Rodgers et al.	
		US- 6,277,666 B1	08-21-2001	Hays et al.	
		US- 6,563,106 B1	05-13-2003	Bowers et al.	
		US- 6,567,715 B1	05-20-2003	Sinclair et al.	
		US- 6,574,033 B1	06-03-2003	Chui et al.	
		US- 2002/0086456 A1	07-04-2002	Cunningham et al.	
		US- 2003/0021523 A1	01-30-2003	De Natale	
		US- 2003/0062332 A1	04-03-2003	Harris et al.	
		US- 2003/0060051 A1	03-27-2003	Kretschmann et al.	
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FOREIGN PATENT DOCUMENTS

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First Named Inventor

Schiek, Richard

Art Unit

Examiner Name

Attorney Docket Number

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NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		SUNGWOOK, CHO, Development of a Geometry-Based Process Planning System for Surface Micromachining, International Journal of Production Research, 2002, Vol. 40/No. 5/MAR, pp. 1275-1293, Institution of Production Engineers.	
		R. SCHIEK and R. SCHMIDT, A New, Topolog Driven Method for Automatic Mask Generation from Three-Dimensional Models, Feb. 23, 2003, Sandia National Laboratory, Computational Sciences Department, Albuquerque, New Mexico.	
		THE NATIONAL ACADEMY OF SCIENCES, 2 Integrated Circuit Based Fabrication Technologies and Materials, Microelectromechanical Systems: Advanced Materials and Fabrication Methods (1997), pp. 14-22, http://www.nap.edu/openbook/0309059801/html .	

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